

**Notice of References Cited**

Application/Control No.

09/870,534

Applicant(s)/Patent Under  
Reexamination  
SRIVASTAVA ET AL

Examiner

Lynette T. Umez-Eronini

Art Unit

1765

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	B	US-5340437	08-1994	Erk et al.	156/639
	C	US-			
	D	US-			
	E	US-			
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	K	US-			
	L	US-			
	M	US-			

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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a) )  
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